

AMENDMENTS TO THE SPECIFICATION:

Please amend the specification as follows:

Add the following new paragraph after the title at page 1:

CROSS REFERENCE TO RELATED APPLICATIONS

This application is a National Phase Application of International Application Number PCT/JP2005/003609, filed March 3, 2005, and claims the priority of Japanese Patent Application No. 2004-063228, filed March 5, 2004, the content of both of which is incorporated herein by reference.

Please amend the first full paragraph, at page 3, line 13 to page 4, line 12 as follows:

However, in recent years, in accordance with sophistication of functions and speed increase of an integrated circuit, a wiring structure has rapidly become more microscopic and thinner and a wiring layer has become extremely thin, and therefore, giving a stylus pressure to a the probe for the inspection as described in the conventional patent document 1 involves a risk of damaging a wiring layer and an insulation layer because the probe penetrates not only the oxide film but also the wiring layer or because of a concentration stress from the probe. On the contrary, decreasing the stylus pressure involves a risk of causing unstable continuity between a the probe and an the electrode pad. Further, though the bumps described in the patent documents 2, 3 can surely break an the oxide film of an electrode pad by the

irregularities, it involves a risk of damaging a the wiring layer and ~~an~~ the insulation layer depending on the stylus pressure, similarly to the case of the patent document 1.

[0007]

The present invention was made to solve the aforesaid problems and an object thereof is to provide a probe and a method of manufacturing the same enabling sure and stable inspection of an object to be inspected ~~with a low stylus pressure~~ by breaking an oxide film with a low stylus pressure, ~~and a method of manufacturing the same.~~

[Means for Solving the Problems]

[0008]

The present invention is a probe that comes into electrical contact with an object to be inspected when inspecting an electrical characteristic of the object to be inspected, the probe including: a probe main body having a contact portion that comes into contact with the object to be inspected; and a plurality of conductive materials each having a tip portion projecting from the contact portion of the probe main body, wherein the contact portion has a contact surface that comes into contact with the object to be inspected, the tip portions are formed to project from the contact surface, a projection length of the tip portions being larger than a thickness of an oxide film formed on a surface of an electrode of the object to be inspected, and the contact surface comes into contact with the surface of the electrode of the object to be inspected to function as a stopper for the tip portions when the tip portions penetrate the oxide film to reach the electrode.

[0009]

~~The contact portion may have a contact surface that comes into contact with the
object to be inspected.~~